Electronic Acknowledgement Receipt				
EFS ID:	1437539			
Application Number:	10659258			
International Application Number:				
Confirmation Number:	3535			
Title of Invention:	Plasma apparatus and method capable of adaptive impedance matching			
First Named Inventor/Applicant Name:	Chien-Hsin Lai			
Correspondence Address:	LOWE HAUPTMAN GILMAN & BERNER, LLP - Suite 310 1700 Diagonal Road Alexandria VA 22314 US 7036841111			
Filer:	Benjamin J. Hauptman/Ayesha Wilson			
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File Listing:

Document Number	Document Description	File Name	File Size(Bytes)	Multi Part /.zip	Pages (if appl.)
1	Amendment - After Non-Final Rejection	2007-01-12-Response.pdf	91410	no	14
Warnings:					

This Acknowledgement Receipt evidences receipt on the noted date by the USPTO of the indicated documents, characterized by the applicant, and including page counts, where applicable. It serves as evidence of receipt

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91410

## New Applications Under 35 U.S.C. 111

similar to a Post Card, as described in MPEP 503.

Information:

If a new application is being filed and the application includes the necessary components for a filing date (see 37 CFR 1.53(b)-(d) and MPEP 506), a Filing Receipt (37 CFR 1.54) will be issued in due course and the date shown on this Acknowledgement Receipt will establish the filing date of the application.

## National Stage of an International Application under 35 U.S.C. 371

If a timely submission to enter the national stage of an international application is compliant with the conditions of 35 U.S.C. 371 and other applicable requirements a Form PCT/DO/EO/903 indicating acceptance of the application as a national stage submission under 35 U.S.C. 371 will be issued in addition to the Filing Receipt, in due course.